

Docket No. AM 1562D1

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Divisional Application of

JOAN WANG

Parent Serial No.: 08/867,229

Parent Filed: June 2, 1997

For: METHOD OF ETCHING HIGH ASPECT  
RATIO OPENINGS IN SILICON

PETITION UNDER 37 CFR 1.84(b)(1)

To: Assistant Commissioner for Patents  
Washington, DC 20231

Sir:

Applicants petition that the Assistant Commissioner accept  
THREE sheets of photomicrographs bearing Figures 3, 4, 5, 6, 7  
and 8 thereon. Three copies of each sheet are attached.

Please charge the Petition fee of \$130.00 to Deposit Account  
13-4542. A duplicate of this Petition is attached.

Respectfully submitted,

JOAN WANG

By

  
Birgit E. Morris

Registration No. 24,484

06/15/01  
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09/882141  
06/15/01

Birgit E. Morris, Esq  
5 Tall Timbers Drive  
Princeton, NJ 08540  
(609) 921-1695

Please continue to send all correspondence to

Patent Counsel  
Applied Materials, Inc.  
PO Box 450A  
Santa Clara, CA 95054

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to The Assistant Commissioner for Patents, Washington, DC 20231, on

June 15, 2001  
Date of Deposit

~~William E. Morris~~  
Name of person making deposit

Signature